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# Electric field enhanced 3D scalable low-voltage nano-spike electroporation system



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#### ABSTRACT

Electroporation (EP) is one of the most widely used methods for the introduction of bio-molecules into the cells due to its high efficiencies, simplicity, and safety. Previous macro- and micro-scale EP systems suffer from drawbacks such as costly and time-consuming fabrication processes, high voltage operation causes undesirable electrochemical reactions, low cell viabilities, and electrode degradation. In this paper, we presented a low-cost three-dimensional (3D) scalable nano-spike electroporation system for efficient molecules delivery with high cell viabilities at low applied voltages. Arrays of 3D Aluminum (Al) nano-spikes (NSPs) were fabricated through scalable, reproducible and cost effective electrochemical anodization and etching processes. Due to scalability of the fabrication process, 3D NSPs were fabricated on chips as well as at the wafer level for large scale processing. 3D nano-spike electroporation (NSP-EP) chips were capable of handling small cell populations (100-500) while NSP-EP wafers can handle large cell populations (10<sup>4</sup>-10<sup>5</sup>). Electroporation at low voltages is obtained due to electric field enhancement at high-aspect-ratio NSPs. With same electric field strength, high EP efficiencies  $\eta_{EP}$  and cell viability  $\phi_{cell}$ (>93  $\pm$  6%) were obtained at more than ten times lower voltages (2 V) on NSP-EP chips as compared to planar electroporation (PEP) devices without NSPs. By optimizing electric pulse parameters and nanospikes dimensions, NSP-EP chip performance was enhanced by minimizing undesirable electrochemical reactions and electrolysis that were observed on PEP devices due to high voltage operations.

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#### 1. Introduction

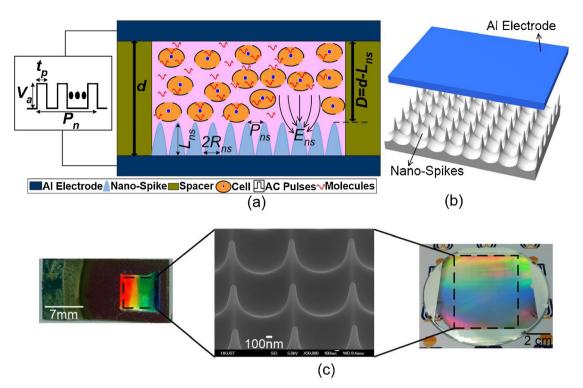
The introduction of exogenous molecules such as proteins, drugs and genetic material with high efficiency and viability through the cell membrane is a critical step in analytical and diagnostic microsystems [1–4]. Different approaches have been used to transfer these molecules, such as chemical, biological or physical methods. Chemical and biological methods are often limited due to low efficiency, toxicity and safety concerns [5–7]. Due to the simplicity, safety and high efficiency; physical methods have been adopted to directly deliver the molecules and agents into the cells [5–8]. The most common and widely used physical method is elec-

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troporation (EP) due to its simplicity, low cost, safety, efficiency, fast delivery, and applicability to diverse cell types and sizes. EP uses electric fields to induce reversible nanopores expansion in the cell membrane so that it becomes permeable to exogenous molecules [9-11]. Besides these advantages, several disadvantages are associated with the conventional electroporation system (cuvette type) due to high voltage requirements to achieve critical electric field for EP  $(E_{FP})$  [12–14]. Due to high voltage operations, conventional EP system undergoes metal ion dissolution [12,13], local pH variation [12,13], joule heating [12,14], local pH variation [12,13], distorted electric field [12], gas and bubble generation [15], sample contamination due to electrode degradation and irreversible electroporation resulted in low EP efficiency electroporation and low cell viability [12–15]. In addition, conventional EP system requires bulky and costly high voltage pulse generators [16], large volumes of sample solutions, expensive reagents, and cells.

Micro-scale EP is getting more attention as compared to conventional bulky EP systems due to several advantages, such as

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**Fig. 1.** Illustration of Nano-Spike Electroporation (NSP-EP) chip, (a) 2D schematic of NSP-EP chip shows electric field enhancement at nano-spikes (NSPs) due to high aspect ratio  $\lambda$  (= $L_{ns}/R_{ns}$ ), (b) 3D schematic of NSP-EP chip and (c) SEM image of arrays of NSPs fabricated on an Aluminum (Al) foil of area of 49 mm<sup>2</sup> and a 4-inch glass wafer.

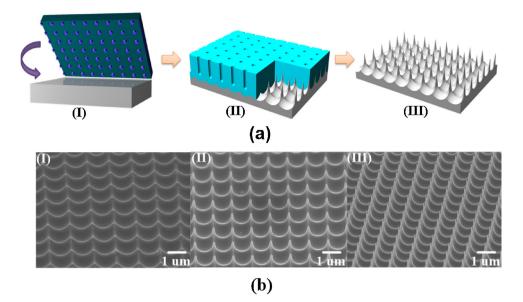
high efficiency, spatiotemporal control, in situ visualization, realtime monitoring, rapid protocol optimization and single-cell EP [12,14,15,17–20]. Critical electric field  $E_{EP}$  was achieved at much lower voltages as compare to conventional EP either by placing electrodes in close proximity (reducing the distance between electrodes) or focusing electric field through small constriction segments and structures in micro-channels or micro-chambers [5,12,14,15]. Micro electrodes in close proximity were placed either in micro-channel or micro-chamber in parallel plate or coplanar configuration [12,14,18,21]. The depth of these 2D electrodes was usually smaller than the size of the cells, so small portion of cells was exposed to an electric field which resulted in electroporation of small sample volume at once [22]. The thin metal layers of these electrodes were not stable and had tendency to decay due to undesirable electrochemical reactions such as gas and bubble generation [15,23]. These issues of 2D electrodes were addressed by fabrication various types of 3D electrodes [14,22]. But the fabrication of these 3D electrodes usually involves complex, time consuming and costly steps [24,25]. Also the separation distance between electrodes in micro-devices is limited by cell sizes [26].

Microelectrodes in close proximity usually suffer from degradation due to electrolysis depending on applied pulse parameters [15,27]. Pulses of high amplitude, duration and number result in the electrolysis of water which causes bubble and gas formation. Due to these undesirable electrochemical reactions, cell viabilities were dropped by sample contamination, pressure exertion by bubbles and arcing [23,28-30]. These problems can be minimized by lowering the average electrical current through increasing the resistance between the electrodes [14]. Constriction segments or structures in the channels were employed so that maximum potential drop was across the cell membrane trapped in these structures instead of in the vicinity of the electrode [14,17,19,31–33]. Although electrode degradation can be minimized but the fabrication of such structures and segments involves complex and costly manufacturing steps [14]. Besides, these constriction segments and structures in micro-channels require expensive equipment and suffer from

channel blocking by cells or bubbles [14,15,27,34,35]. The average electric current can also be reduced by applying AC pulses with low amplitude and shorter duration, but pulse parameters should be optimized to achieve high efficiencies and cell viabilities in addition to minimizing electrochemical reactions [15,34,36,37].

Nanostructures such as nano-tubes, nano-wires, nano-pillars, and nano-straws electrodes fabricated with different materials have been used recently for EP [38-48]. EP on these electrodes has been achieved at reduced voltages as compared to planar electrodes without nano-structures [39-48]. EP at reduced voltages has been performed due to high-aspect-ratio nano-structures which resulted in the enhanced electric field. Rojas-Chapana et al. used multi-walled carbon nano-tubes (MWCNT) for microwave based electroporation of gram-negative bacteria [39]. They specify the "lightening rod effect" for electric field localization at the CNT tips. Raffa et al. used MWCNT to achieve reversible electroporation at the lower electric field of  $0.05 \, \text{kV/cm}$  with the efficiency of  $\sim 80\%$ as compared to macro plate electrodes (0.5–100 kV/cm) [41]. Chen et al. fabricated ITO electrodes with a gap of 500 nm to localized electric field for single cell and achieved cell viabilities of 80-95% at applied voltages of 12 V [43]. Xie et al. used alumina nano-straw electroporation system and achieved efficiency of 95% at 20 V [46].

Although the nano-structured electrodes enabled the enhanced EP at reduced voltages as compared to planar electrodes, the applied voltages used in the previous works are still in the range of tens of volts to achieve EP with high efficiency and cell viability [39–48] (see supplementary information (SI), Table S1). This is highly undesirable in portable lab-on-chip (LOC), micro total analysis system ( $\mu$ TAS) and smartphone-based systems with limited power source [1,2,4,49]. One of the bottlenecks in the integration of nano-structures on the microsystems is the difficulties in handling and positioning the nano-structures at the exact desired location to fabricate reproducible, periodic and uniform nano-structures [4]. Furthermore, the fabrication techniques employed in the fabrication of these nano-structures using conventional techniques are complex, costly, time consuming and non-reproducible [4]. It is



**Fig. 2.** (a) Schematics of 3D periodic nano-spike arrays fabrication process, (I) the cleaned Al foil substrate was imprinted using a silicon mold with squarely patterned pillars resulted in periodic nano-holes on substrate, (II) imprinted substrate was anodized and then etched in a mixture of phosphoric acid and chromic acid for the fabrication of nano-spike arrays, and (III) fabricated 3D nano-spike arrays on substrate. (b) SEM images of nano-spike electrodes with different lengths *L*<sub>ns</sub> of, (I) 350 nm, (II) 750 nm, (III) 1100 nm.

highly desirable to establish simple, inexpensive, reliable and scalable fabrication techniques for fabrication of reproducible, periodic and uniform nano-structures to be used in their integration on microsystem and potential mass production [1,2,4,49].

In this work, we present a 3D scalable nano-spike based EP system which utilized highly ordered self-aligned 3D Aluminum (Al) nano-spike (NSP) arrays fabricated through electrochemical anodization and etching processes. Due to their simplicity, low cost and scalability, electrochemical anodization and etching processes have been used recently for the fabrication of self-aligned highly ordered 3D nano-structures [50]. Nano-structures fabricated through electrochemical anodization and etching processes using anodic alumina membrane(AAM) as template showed great potential applications in the field of magnetism, electronics, opto-electronic, photovoltaic, medical, and biology [50–55]. Alumina is recognized as bio-compatible material and used in hip arthroplasty [56], tissue engineering especially for skin replacement [57], bone implant [58], and cell culture and proliferation [59].

We fabricated a 3D scalable nano-spike based EP system which utilized nano-spike electroporation (NSP-EP) chips and a computer-controlled electric pulse generator (Fig. 1) for efficient intracellular molecules delivery with high cell viabilities at low pulse amplitudes and durations. NSP-EP chips have highly-ordered 3D Al NSP arrays with controllable dimensions such as length,  $L_{ns}$ , base radius,  $R_{ns}$ , and pitch,  $P_{ns}$  (spike to spike distance). These NSPs were fabricated on low-cost commercial Al foils through simple, scalable, reproducible and cost effective electrochemical anodization and etching processes (Fig. 2). Highly-ordered 3D NSPs with high-aspect-ratios,  $\lambda (=L_{ns}/R_{ns})$  have been fabricated (Fig. 2). The electric field has been localized at NSPs due to high  $\lambda$  with an enhancement factor  $\alpha$  as compared to planar EP devices (PEP) (Fig. 3). NSP-EP chips have achieved high EP efficiencies  $\eta_{EP}$  and cell viability  $\phi_{cell}$  at more than ten times reduced pulse amplitudes through localized electric field  $E_{ns}$  as compared to the planar EP devices (PEP) without NSPs (Fig. 4). The employment of electrochemical fabrication process, optimized AC electric pulses with low amplitudes and short durations minimize undesirable electrochemical reactions, such as gas and bubble generation and electrolysis of cells on NSP-EP chips (Fig. 4). Due to scalability of fabrication process, highly ordered 3D NSPs were fabricated on small

chips as well as on wafers to process samples for microsystems as well as for high throughput applications (Fig. 1).

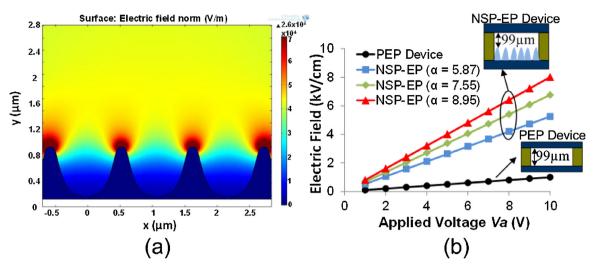
#### 2. Material and methods

#### 2.1. 3D nano-spike arrays fabrication

Process steps involved in the fabrication of highly-ordered 3D Al NSP arrays are as follows [51]. First of all, low-cost commercial Al foils (99.99% Alfa Aesar, MA, USA) with a thickness of ca 250 µm were cut into  $2 \times 1$  cm<sup>2</sup> pieces. These pieces were then cleaned with acetone followed by isopropyl alcohol and deionized (DI) water rinsing. The cleaned pieces were electrochemically polished in a 1:3 (v:v) mixture of perchloric acid and ethanol for 4 min at 5 °C. The electropolished Al foils were imprinted by a silicon stamp to nano-imprint the squarely ordered nanoindentation for location definition of the anodic alumina (AAM) pores (Fig. 2(a)). Al foils had perfect squarely ordered nano-indentation after nano-imprint (Fig. 2(a)). Silicon stamp had squarely patterned pillar with a height of  $\sim$  200 nm, a diameter of 500 nm and a pitch  $P_{ns}$  of 1.2  $\mu$ m. The substrates were then anodized in a home-built anodization setup in a mixture of citric acid, ethylene glycol, and phosphoric acid. Different anodization conditions were used to achieve different heights of NSPs i.e. the electrolyte voltage was 480 V, while the anodization time was 180. The anodized AAM layer was then etched away in a mixture of phosphoric acid (6%) and chromic acid (1.5%) at 63 °C for 50 min (Fig. 2(b)) to obtain perfectly ordered 3D NSP arrays (Fig. 2(b)). 3D Al NSP electrodes were cleaned with DI water and dried with air.

#### 2.2. NSP-EP chip fabrication

Al foils with a thickness of  $ca 250 \,\mu\text{m}$  and area of  $2 \times 1 \,\text{cm}^2$  were cleaned, and NSPs were fabricated on an area of  $7 \times 7 \,\text{mm}^2$  using nano-imprinting, electrochemical anodization and etching as discussed in the previous section. Note that this fabrication technique is scalable and it ranges from a small chip to a wafer (Fig. 1(c)). The top electrode was separated from the bottom electrode through a spacer (3 M Orange Polyimide electrical insulation tape) with thickness *d* of 100  $\mu$ m (Fig. 1(a)). This spacer not only insulated two



**Fig. 3.** (a) Numerical simulation of the electric field distribution between nano-spike array electrodes ( $\lambda = 2.5$ ) using COMSOL at applied voltage  $V_a = 4$  V. The simulation shows enhanced electric field  $E_{ns}$  with enhancement factor  $\alpha$  depending on aspect ratio  $\lambda$  of NSPs, (b) Electric field as function of applied voltages  $V_a$  for planar electroporation (PEP) device without nano-spikes and NSP-EP devices with different  $\alpha$ .

electrodes but also formed a micro-well to inject cell suspension and molecules for EP (Fig. 1(a)-(b)). Before EP experiments, NSP-EP chips were sterilized with 75% ethanol solution, rinsed with DI water and then dried in a 65 °C oven.

#### 2.3. Cell culturing

Human cervical cancer (HeLa) cell line was used in the EP experiments to characterize EP efficiency  $\eta_{EP}$ , cell viability  $\phi_{cell}$  and operating conditions of NSP-EP chips. HeLa cells were grown as a monolayer in a 60 mm petri dish in Eagle's minimal essential medium (EMEM) (CCL-2<sup>TM</sup>, ATCC, VA, USA), supplemented with 10% fetal bovine serum (FBS) (ATCC, VA, USA) and 1% Streptomycin/Penicillin (GIBCO<sup>®</sup>, Invitrogen Inc., USA) at 37 °C and 5% CO<sub>2</sub>. To perform EP experiments, HeLa cells were re-suspended in the EP medium (EMEM supplemented with 10% FBS). To get cell suspension, the EMEM medium was vacuumed; cells were washed twice with PBS and the attached cells on petri dish were trypsinized by 0.25% trypsin/EDTA (GIBCO<sup>®</sup>, Invitrogen Inc., USA) for 3–5 min at 37 °C. The trypsinized cells were centrifuged at 1200 rpm at room temperature for 3 min and concentration of HeLa cells were adjusted to 1 × 10<sup>5</sup> cells/mL in the cell suspension.

#### 2.4. Experimental setup

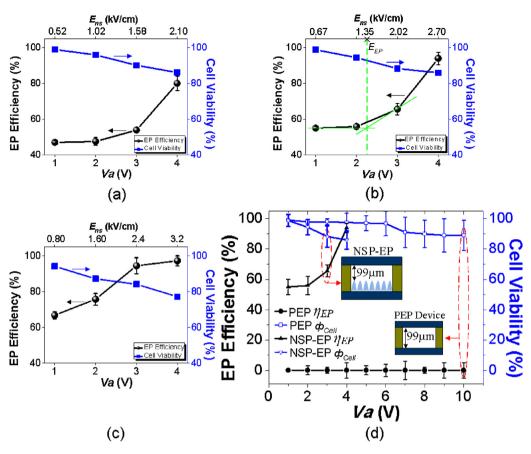
The pulsed electric field with adjustable pulse amplitude ( $V_a$ ), pulse duration ( $t_p$ ) and pulse number ( $P_n$ ) was applied to the NSP-EP chips using a PCI 6110 DAQ card (National Instrument, TX, USA) and a Labview program (see SI, Fig. S1). The applied pulse signal variation was  $\pm 0.02$  V. An Olympus IX70 inverted fluorescent microscope and a QImaging Retiga 1300C digital CCD camera (Burnaby, B.C., Canada) were used for in situ visualization of the cell's response (see SI, Fig. S1). The 100 W mercury lamp with sets of fluorescence filters (excitation by a 515–565 nm bandpass filter and the emission by a 550–655 nm bandpass filter) was used for the optical microscopy of the cells on the NSP-EP chips. Sets of bright field and fluorescent micrographs were acquired by an image capture card. These images have been used to determine the  $\eta_{EP}$  and  $\phi_{cell}$  as functions of  $V_a$ ,  $t_p$  and  $P_n$ .

#### 2.5. Dual acridine orange/propidium iodide fluorescent staining

Acridine Orange and Propidium Iodide (AO/PI; Sigma, St Louis, MO, USA) dual fluorescent dye staining was used to determine electroporation efficiency  $\eta_{EP}$ . Both Acridine Orange (AO) and Propidium Iodide (PI) are nuclear staining dyes. AO is a membrane permeable dye and stains all cells and emits green fluorescence. PI is membrane impermeable dye which can enter cells membranes with expanded nano-pores and emits red fluorescence. Cells were suspended in EP medium and dual fluorescent AO/PI staining solution containing 0.7  $\mu$ g/ml AO and 1  $\mu$ g/ml PI was added. This cell suspension was injected to NSP-EP chips and electric pulses with different  $V_a$ ,  $t_P$  and  $P_n$  were applied. Electroporated cells appeared red under fluorescent mode as PI molecules entered the cells through expanded nano-pores and bonded to the DNA/RNA while non-electroporated cells appeared green. Sets of fluorescent micrographs were acquired 5 min after application of electric pulses to allow the entrance of PI dye into cells. The acquired images were processed to determine  $\eta_{EP}$  as a function of different electric pulse parameters.  $\eta_{EP}$  was calculated by counting the cells appeared red under fluorescent mode over the total cells.

#### 2.6. Dual acridine orange/ethidium bromide fluorescent staining

Acridine Orange and Ethidium Bromide (AO/EB; Sigma, St Louis, MO, USA) dual fluorescent dye staining was used to determine cell viabilities  $\phi_{cell}$ . Both Acridine Orange (AO) and Ethidium Bromide (EB) are nuclear staining dyes. AO is a membrane permeable dye and stains all cells and emits green fluorescence. EB is membrane impermeable dye which can enter cells with compromised membranes and emits red fluorescence. When cells are stained with dual AO/EB dyes, live cells emit green fluorescence while dead cells exhibit orange-yellow fluorescence due to loss of membrane integrity. To determine  $\phi_{cell}$ , cell suspension without AO/EB was injected to NSP-EP chips and electric pulses with different  $V_a$ ,  $t_P$ and  $P_n$  were applied. Dual fluorescent AO/EB staining solution containing 0.5  $\mu$ g/ml AO and 0.5  $\mu$ g/ml EB was added to cell suspension 5 min after application of electric pulses to avoid false reading from reversibly electroporated cells. Dead cells appeared orange-yellow under fluorescence due to binding of EB dye with DNA/RNA either inside cytoplasm or outside ruptured cell membrane. Sets of fluorescent micrographs were acquired and processed to determine



**Fig. 4.** EP efficiency ( $\eta_{EP}$ ) and cell viability ( $\varphi_{cell}$ ) as a function of applied voltage ( $V_a$ ) and localized electric field ( $E_{ns}$ ) with pulse duration  $t_P$  of 2 ms on NSP-EP chips with different enhancement factor  $\alpha$ , (a)  $\alpha$  = 5.87, (b)  $\alpha$  = 7.55, and (c)  $\alpha$  = 8.95, and (d)  $\eta_{EP}$  and  $\varphi_{cell}$  on NSP-EP chip ( $\alpha$  = 7.5) and PEP devices as a function of  $V_a$  and  $t_p$  = 2 ms.

 $\phi_{cell}$  as a function of different electric pulse parameters.  $\phi_{cell}$  was calculated by counting cells appeared orange-yellow under fluorescence over the total cells.

#### 2.7. Statistical analysis

Each data point for  $\eta_{EP}$  and  $\varphi_{cell}$  was obtained by analyzing at least 100 cells and each experiment was repeated at least three times. The standard deviation between repeated experiments was shown as error bars.

#### 3. Results and discussion

#### 3.1. 3D NSP-EP system

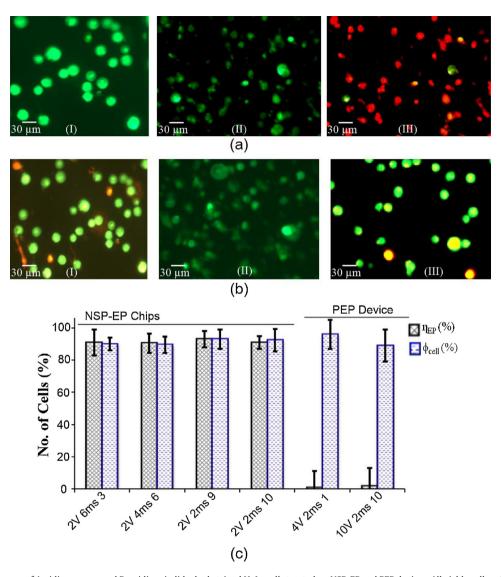
The 2D and 3D schematics of NSP-EP chip architecture are shown in Fig. 1(a and b). NSP arrays have been fabricated on the Al electrodes with length  $L_{ns}$ , base radius  $R_{ns}$  and pitch  $P_{ns}$ . The top and bottom electrodes are separated by a spacer with a thickness of d (=100  $\mu$ m) resulted in the formation of micro-well for cell sample and molecules injection (Fig. 1(a)). The gap between tip of the NSPs and the counter electrode of the NSP-EP is defined as  $D (=d - L_{ns})$ . Due to high aspect ratio  $\lambda (=L_{ns}/R_{ns})$  of NSPs; the applied electric field  $E_a$  is enhanced  $E_{ns}$  by enhancement factor  $\alpha$ . The  $\alpha$ , hence enhanced electric field  $E_{ns}$  was controlled by controlling dimensions of NSPs. Electric pulses with adjustable pulse amplitudes  $V_a$ , pulse durations  $t_p$  and pulse number  $P_n$  have been applied between two electrodes of NSP-EP chips through a PCI 6110 DAQ card (National Instrument, TX, USA) and a Labview program. Sets of fluorescent micrographs were acquired after EP by an image capture card using an Olympus IX70 inverted fluorescent microscope and a QImaging Retiga 1300C digital CCD camera (Burnaby, B.C., Canada). These acquired images were used to determine the  $\eta_{EP}$  and  $\varphi_{cell}$  as functions of electric pulse parameters ( $V_a, t_p$  and  $P_n$ ) and NSPs dimensions. Due to  $E_{ns}$ , NSP-EP chips offer the advantage of achieving high  $\eta_{EP}$  and  $\varphi_{cell}$  at reduced pulse amplitudes and shorter pulse durations. EP with low pulse amplitudes and shorter pulse durations minimizes undesirable electrochemical reactions such as gas and bubble generation and electrolysis of cells.

#### 3.2. Scalable 3D NSP-EP platform

The 3D NSP array fabrication process is highly scalable and it can range from chip to wafer level. In this work, a typical size of NSP-EP chip is *ca* 7 × 7 mm<sup>2</sup> (Fig. 1(c)). We have successfully fabricated 3D Al NSP arrays on a 4-inch glass wafer (Fig. 1(c)). 3D NSP-EP chips were capable of handling small cell populations (100–500) in  $\mu$ L. The throughput can be scaled up to handle large cell populations (10<sup>4</sup>–10<sup>5</sup>) on NSP-EP wafers. This simple, low-cost, scalable, reproducible and reliable process is highly attractive for cost-effective portable  $\mu$ -TAS, LOC, and smartphone-based systems as well as for high throughput and large population applications.

#### 3.3. 3D NSP-EP chips

3D NSP arrays fabrication process for EP was modified from elsewhere [52–55]. It consists of nano-imprint approach in conjunction with two major steps that are scalable electrochemical anodization and etching [60] (Fig. 2(a)). First, clean Al foils were anodized in a mixture of citric acid and ethylene glycol with a DC voltage of 600 V. This anodization step resulted in the formation of anodic alumina membrane (AAM) on an Al substrate (Fig. 2(aII)). The AAM



**Fig. 5.** (a) Fluorescent images of Acridine orange and Propidium iodide dual stained HeLa cells treated on NSP-EP and PEP devices. All viable cells exhibit green fluorescence while electroporated cells exhibit red-orange fluorescence due to pore formation on cell membrane, (1) EP on PEP device at  $V_a = 5$  V and  $t_p = 2$  ms, (II) NSP-EP chips ( $\alpha = 7.5$ ) before EP, and (III) EP on NSP-EP chips ( $\alpha = 7.5$ ) at  $V_a = 2$  V,  $t_p = 2$  ms and  $P_n = 9$ . (b) Fluorescent images of Acridine orange and Ethidium bromide dual stained HeLa cells treated on NSP-EP and PEP devices. Viable cells exhibit green fluorescence while lysed cells exhibit orange-yellow fluorescence due to loss of membrane integrity, (1) PEP device at  $V_a = 5$  V and  $t_p = 2$  ms, (III) NSP-EP chips ( $\alpha = 7.5$ ) before EP, (IIII NSP-EP chips ( $\alpha = 7.5$ ) at  $V_a = 2$  V,  $t_p = 2$  ms and  $P_n = 9$ . (c) Optimized electric pulse parameter ( $V_a t_p P_n$ ) to obtain high  $\eta_{EP}$  and  $\varphi_{creff}$  on NSP-EP chip ( $\alpha = 7.5$ ). (For interpretation of the references to colour in this figure legend, the reader is referred to the web version of this article.)

had perfect squarely ordered pores which acted as a template for fabrication of 3D NSP arrays. The AAM layer was then chemically etched away in a mixture of phosphoric and chromic acid resulted in 3D NSP arrays (Fig. 2(alII)). In this work, citric acid has been used as an electrolyte resulted in better stability [52–55]. Stability of electrolyte was further improved by mixing with ethylene glycol, and the anodization voltage was increased up to 600 V [52–55]. Further details of scalable anodization and etching process steps can be found in the Materials and Methods section.

The length of NSPs can also be precisely controlled by controlling the thickness of AAM and anodization time. The maximum achievable length  $L_{ns}$  of NSPs was about ~1100 nm after 360 min anodization. Fig. 2(b) shows sixty degrees tilted SEM images of NSP array electrodes with  $L_{ns}$  of 350, 750, and 1100 nm fabricated by 30, 180, and 360 min anodization, respectively and has pitch  $P_{ns}$  of 1.2 µm. NSP arrays fabricated using above-mentioned electrochemical process has several advantages including periodicity, self-organization, scalability, reproducibility, and high-aspect-ratio  $\lambda$ .

#### 3.4. Electric field enhancement

Numerical simulations were performed to evaluate the electric field enhancement especially near the tips of NSPs. A commercial finite element method (FEM) package (COMSOL Multiphysics 4.2, COMSOL Ltd., USA) was used for electric field distribution simulation. The profile of NSPs was extracted with the help of extract profiles tool using AFM images of NSPs. The extracted coordinates of NSPs were then exported to COMSOL. Materials were selected for NSP electrodes which are Al in this case. The electrodes were separated by a distance d and space between the electrodes was considered as cell suspension medium. The relative permittivity and conductivity of cell suspension medium were assumed to be  $77.4 \pm 5\%$  and  $1.7 \text{ S/m} \pm 10\%$ , respectively [60]. The fixed potential between the electrodes was used as the boundary condition. The fixed potential between the electrodes was applied by selecting 2D stationary electrostatics physics in COMSOL. Numerical simulations illustrate that the applied electric field  $E_a$  is enhanced by

enhancement factor  $\alpha$  and enhanced electric field  $E_{ns}$  is very strong near tips of NSPs as shown in Fig. 3(a).

In our EP experiments, high  $\eta_{EP}$  and  $\Phi_{cell}$  have been achieved at lower pulse amplitudes due to enhanced electric field  $E_{ns}$  at NSPs. The electric field at the tips of the NSPs is enhanced due to their high-aspect-ratio $\lambda$ . The localized enhanced electric field  $E_{ns}$  can be estimated using following relation [39,61]:

 $(1)E_{ns} = E_a \times \alpha \times \gamma$ 

where  $\alpha$  is the electric field enhancement factor,  $E_a$  is the applied electric field given by ratio of applied amplitude  $V_a$  to distance between electrodes D,  $\gamma$  is the correction factor considering the electrochemical impedance near the fluid-electrode interface [62,63].

Several models have been proposed to estimate  $\alpha$  based on the geometries of nanostructures [61]. In our case, by modelling NSP as a hemi-ellipsoid with a length of  $L_{ns}$  and a base radius of  $R_{ns}$ , the enhancement factor  $\alpha$  can be predicted as a function of the NSP aspect-ratio $\lambda$  [61]:

$$\alpha = \xi^3 / [\{\lambda \ln(\lambda + \xi)\} - \xi]$$
<sup>(2)</sup>

where  $\xi = (\lambda^2 - 1)^{1/2}$  and  $\lambda$  is NSP aspect-ratio and given by ratio of  $L_{ns}$  to  $R_{ns}$ . As previously discussed that NSPs were fabricated with controlled and reproducible dimensions with different  $\lambda$ . It is clear from equation 2 that  $\alpha$  is function of  $\lambda$  and increase exponentially with $\lambda$ . This suggests that very high  $\alpha$  can be achieved by selecting appropriate  $\lambda$  as per equation 2. But due to fabrication limitations, we are able to achieve  $\lambda$  up to 3. For NSPs with  $\lambda$  ranging from 2 to 3,  $\alpha$  was estimated using equation 2 and it ranged from ~5.9 to 8.9 as shown in Fig. 3(b).

The inter-electrode distance of the planar EP (PEP) device was controlled by a spacer with a thickness of *d*. On the other hand, the gap between the tip of spikes and the counter electrode of NSP-EP device is the space thickness minus the length of the nanospike, i.e.,  $D = d - L_{ns}$ . In planar electroporation (PEP) device without NSPs, the applied electric field  $E_{planar}$  can be estimated as the ratio of the applied voltage  $V_a$  to the distance between electrodes D  $(E_{planar} = V_a/D)$ . In the case of our NSP-EP device, the electric field at the tips of the nano-spike is highly enhanced due to their high aspect ratio of  $\lambda$  with the enhancement factor  $\alpha$ . In order to compare electric field for PEP device and NSP-EP devices, same interelectrode distance D ( $\sim$ 99  $\mu$ m) was considered. Localized electric field  $E_{ns}$  at NSPs was determined using equation 1. From Fig. 3(b), it is clear that electric field was enhanced at NSP-EP devices as compared to planar electrode devices due to  $\alpha$ . This implies that a specific electric field can be achieved at reduced voltages on NSP-EP devices as compared to PEP devices. For example, electric field of 1 kV/cm can be accomplished at 10 V for PEP device, at  $\sim$ 2 V for NSP-EP device with  $\alpha$  of 5.87, at  ${\sim}1.5$  V for NSP-EP device with  $\alpha$  of 7.55 and at  $\sim$ 1.3 V for NSP-EP device with  $\alpha$  of 8.95 (Fig. 3(b)).

For the interelectrode distance of 99  $\mu$ m and the applied voltage  $V_a$  of 4 V, the estimated effective electric field  $E_a$  for the PEP device is 0.4 kV/cm which is below critical electric field to induce EP in HeLa cells (1.6 kV/cm for single pulsed EP for HeLa cells) according to our previous study of EP phase diagram for HeLa cells [22]. For the NSP-EP chip, the enhanced electric field  $E_{ns}$  for  $\alpha$  of 7.55 at 4 V is estimated as 2.7 kV/cm. Therefore, at the same applied voltage of 4 V, the effective electric field of the NSP-EP chip is larger than 1.6 kV/cm. In this paper using NSP-EP chips, we verified that for HeLa cells, we also achieved a critical electric field strength of 1.5–1.6 kV/cm for 2 ms at 2.3 V.

#### 3.5. Electroporation on NSP-EP chips

Cell permeabilization can be induced only when applied electric pulse parameters  $V_a$ ,  $t_P$  and  $P_n$  are well above their critical values [22,64]. Transient and localized micro structural changes and nanopore generation in the cell membrane is initiated by the electric field strength which is determined by the pulse amplitude  $V_a$  at or above critical value. The pulse duration  $t_P$  and number  $P_n$  provides the required time for nano-pore growth. The time duration and density of nanopores on cell membranes highly depend on  $V_a$ ,  $t_P$ , and  $P_n$ . It is highly desirable to optimize these electric pulse parameters to achieve high  $\eta_{EP}$  and  $\phi_{cell}$  simultaneously at low applied amplitudes in order to avoid undesirable electrochemical reactions and electrolysis of cells [37].

In this study, we applied rectangular AC electric pulses with adjustable  $V_a$  of 0–4V,  $t_p$  of 0–8 ms and  $P_n$  of 1–10 on NSP-EP chips with different enhancement factor  $\alpha$  (5.87, 7.55 and 8.95) to study EP at reduced voltages. Cell permeabilization was detected through the digital fluorescence microscopy. The  $\eta_{\text{EP}}$  were quantified by dual AO/PI fluorescent staining (Fig. 5(a)) while the  $\phi_{\text{cell}}$  were quantified by dual AO/EB fluorescent staining (Fig. 5(b)).

Fluorescence micrographs before EP have no red fluorescence due to impermeability of cell membrane to PI dye molecules (Fig. 5(all)). After the application of the electric pulses above a critical value, cell membrane became permeable due to the expansion of nano-pores on cell membranes by an electric field. PI molecules entered the cells through expanded nano-pores and bound with DNA/RNA. Electroporated cells exhibited red fluorescence while the non-electroporated cells exhibited green fluorescence (Fig. 5(alII)). The fluorescence intensity increased quickly in first few minutes due to fast diffusion of PI dye molecules into the cells through the expanded nano-pores. After 3–4 min, the fluorescence reached a saturated value as the concentration of PI dye molecules achieved equilibrium state (see SI, Fig. S2).

The EP process can be divided into three phases (Fig. 4(b)). When applied electric field was smaller than the critical value  $E_{EP}$ ; the electric field was unable to induce enough nanopores on the cell membrane. No noticeable change in fluorescence intensity was observed at this stage (see SI, Fig. S3(a)) and  $\eta_{EP}$  is very low at this stage. When applied electric field is above critical value  $E_{EP}$ , the electric field is strong enough to induce nanopores on cell membranes, and PI molecules can enter the cell through these pores. More and more cells exhibited stronger fluorescence with small increase in applied pulse amplitude  $V_a$  (see SI, Fig. S3(b)-(c)). The  $\eta_{EP}$  increased with large slope in this phase (Fig. 4b). The final stage was the saturation of fluorescence intensity;  $\eta_{EP}$  reached its maximum value. Further increase of pulse amplitude  $V_a$ , resulted in a decrease of cell viabilities.

#### 3.6. Critical electric field for EP

From the above analysis, it is clear that there is critical value of the electric field for EP,  $E_{EP}$ , above which  $\eta_{EP}$  increased with large slope due to the influx of molecules into the cells through induced nano-pores.  $E_{EP}$  is different for different pulse duration  $t_P$  that is smaller for longer  $t_P$  and larger for shorter  $t_P$  (see SI, Fig. S4). For specific  $t_P$ ,  $E_{EP}$  can be defined as the electric field corresponding to the onset of the increasing slope of the EP efficiency curve [30,64]. The  $E_{EP}$  has been achieved at  $V_a > 10$  V on a PEP device (Fig. 4(d)). As stated before, localized electric field  $E_{ns}$  increases with increasing  $\alpha$  which implies that any specific electric field can be achieved at reduced voltages with increasing $\alpha$ .  $E_{EP}$  has been made at much lower voltages at higher  $\alpha$ . For the NSP-EP chip with  $\alpha$  of 5.87,  $E_{EP}$ has been accomplished at  $V_a = 3$  V (Fig. 4(a)). Similarly for  $\alpha$  of 7.55,  $E_{EP}$  has been reached at  $V_a = 2.3$  V (Fig. 4(b)) and for  $\alpha$  of 8.95,  $V_a$ has been reduced to  $\sim 1$  V (Fig. 4(c)).  $E_{EP}$  has been achieved at 4–13 times lower voltages on NSP-EP chips with different  $\boldsymbol{\alpha}$  as compared to PEP devices.

#### 3.7. Effect of enhancement factor on NSP-EP chip performance

Although the EP efficiency  $\eta_{EP}$  increases by increasing the electric field enhancement factor $\alpha$ , the cell viability  $\varphi_{\textit{cell}}$  decreases at higher  $\alpha$  (Fig. 4). If  $\alpha$  is too small,  $\phi_{cell}$  is high but  $\eta_{EP}$  is lower than 80% (Fig. 4(a)). If  $\alpha$  is too high,  $\eta_{EP}$  is also high but  $\phi_{cell}$  is low due to very high localized electric field (Fig. 4(c)). So an optimized value of  $\alpha$  should be selected and selection of  $\alpha$  depends upon application. For example, NSPs with higher  $\alpha$  values can be chosen for applications where high  $\phi_{cell}$  are not required or for electric cell lysis applications [65]. For applications where high  $\eta_{EP}$  and  $\phi_{cell}$ are required, NSPs with medium  $\alpha$  can be selected. NSPs with  $\alpha$  of 7.55 showed higher  $\eta_{EP}$  and  $\phi_{cell}$  simultaneously as compared to NSP-EP chips with other  $\alpha$  and PEP devices (Fig. 4). EP experimental results demonstrated that EP on NSP-EP chips can be achieved at five times reduced voltages with high  $\eta_{EP}$  and  $\phi_{cell}$  as compared to the PEP device for single pulse (Fig. 4(d)). Bubble generation was observed on PEP devices due to high voltage operation, and this was avoided on NSP-EP chip due to low voltage operation. NSPs with  $\alpha$  of 7.55 were selected as it provided higher  $\eta_{EP}$  and  $\phi_{cell}$ simultaneously for further studies in following sections.

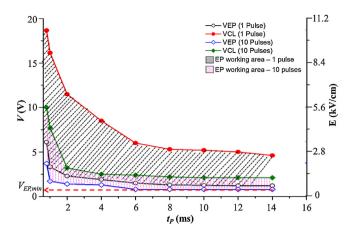
# 3.8. Effect of electric pulse parameters on NSP-EP chip performance

The  $\eta_{EP}$  and  $\varphi_{cell}$  are highly influenced by electric pulse parameters, such as  $V_a$ ,  $t_P$  and  $P_n$ . Higher pulse amplitude  $V_a$ , longer pulse duration  $t_p$  and higher pulse number  $P_n$  resulted in higher permeability, hence higher  $\eta_{EP}$ . But cell viabilities  $\varphi_{cell}$  decreased with higher  $V_a$ , longer  $t_p$  and higher  $P_n$  with increased permeabilities (see SI, Fig. S4-S5). There is a tradeoff between  $\eta_{EP}$  and  $\varphi_{cell}$  and selection of electric pulse parameters depends on the biological application of interest. An optimized value of electric pulse parameters should be selected for high  $\eta_{EP}$  and  $\varphi_{cell}$  simultaneously for efficient EP. For single pulse of 2 ms, 4 V was chosen as the optimal value at which high  $\eta_{EP}$  and  $\varphi_{cell}$  was achieved (Fig. 4(b)).

It was observed that  $\eta_{EP}$  increased by increasing  $t_P$  and  $P_n$  and  $\phi_{cell}$  dropped more quickly by increasing  $t_P$  as compared to increasing  $P_n$  (see SI, Fig. S4-S5). At same pulse amplitude and pulse duration, higher  $\eta_{EP}$  were achieved with increasing  $P_n$ . For  $t_p$  of 2 ms and  $V_a$  of 2 V,  $\eta_{EP}$  was 56% for  $P_n$  of 1 and  $\eta_{EP}$  increased to 91% for  $P_n$ of 10 with same applied  $t_p$  and  $V_q$  (see SI, Fig. S5). In addition, a specific  $\eta_{EP}$  was achieved at lower voltages by increasing pulse number  $P_n$ .  $\eta_{EP}$  of >90% was achieved at 4 V for  $P_n$  = 1 and  $\eta_{EP}$  of >90% were achieved at 2 V for  $P_n = 10$  that is half the applied amplitude for  $P_n = 1$ (see SI, Fig. S5). High  $\eta_{EP}$  (>93 ± 5%) was achieved at NSP-EP chips ( $\alpha$  = 7.55) at low V<sub>a</sub> of 2 V, t<sub>p</sub> of 2 ms and P<sub>n</sub> of 9 as compare to PEP devices at which  $\eta_{EP}$  was almost zero at  $V_a$  of 5 V (Fig. 5(a)). Besides, high  $\phi_{cell}$  (>93 ± 6%) was achieved at NSP-EP chips ( $\alpha$  = 7.55) at low  $V_a$  of 2 V,  $t_p$  of 2 ms and  $P_n$  of 9 as compare to PEP devices (Fig. 5(b)). At PEP devices,  $\eta_{EP}$  was ~0% at  $V_a$  of 10 V while  $\phi_{cell}$  was around 89% (Fig. 5(c)). By optimizing electric pulse parameters, we are able to achieve high  $\eta_{EP}$  and  $\phi_{cell}$  (>93 ± 6%) at low  $V_a$  of 2 V and  $t_p$  of 2 ms for  $P_n$  of 9 and 10 at NSP-EP chips ( $\alpha$  = 7.55) (Fig. 5(c)).

#### 3.9. Undesirable electrochemical reactions

We performed electroporation of HeLa cells on PEP device and NSP-EP chips with same device dimensions and interelectrode distance.  $\eta_{EP}$  and  $\phi_{cell}$  were determined after application of different electric pulse parameters. The critical electric field for EP values for PEP and NSP-EP chip were determined from  $\eta_{EP}$  and  $\phi_{cell}$  curves. For NSP-EP chips, high  $\eta_{EP}$  and  $\phi_{cell}$  (>93 ± 6%) were achieved at



**Fig. 6.** The phase diagram for EP and electric cell lysis of HeLa cells on NSP-EP chips with  $\alpha$  = 7.5 for 1 and 10 pulses. Phase diagram shows the critical electric field strength and voltages for EP ( $E_{EP}$ ,  $V_{EP}$ ) and electric cell lysis ( $E_{CL}$ ,  $V_{CL}$ ) on NSP-EP chip for different pulse duration and number. Minimum  $V_{EP}$  ( $V_{EP,min}$ ) is obtained at 0.8 V with  $P_n$  of 10 and  $t_p$  of 6 ms or above.

low applied amplitudes (2V) while for PEP device at 10V;  $\eta_{EP}$  was ~0% (Fig. 4(d)).  $E_{EP}$  has been achieved at  $V_a > 10$  V on a PEP device (Fig. 4(d)). Due to the NSP's enhanced electric field,  $E_{EP}$  has been achieved at  $V_a = 2.3$  V for  $t_p$  of 2 ms and  $P_n$  of 1 on an NSP-EP chip ( $\alpha = 7.55$ ) (Fig. 4(d)).  $E_{EP}$  has been achieved on a NSP-EP chip ( $\alpha = 7.55$ ) at  $V_a = 0.8$  V for  $P_n$  of 10 and for  $t_p$  of 6 ms and above. This is five to twenty times lower as compared to the PEP device (Fig. 6).

Relatively high voltage (few tens of volts) in macro and micro EP devices resulted in low reliability and device failure due to joule heating, electrolysis, gas bubble generation, local pH variations, etc [60]. Cells were found damaged and lysed during EP process due to gas bubbles generation which resulted in local pH variations and violent hydrodynamic forces due to bubble generation or collapse process [30,60]. Gas bubble generation was observed on PEP device when high voltages (>10 V) are applied to achieve high  $\eta_{EP}$  but  $\phi_{cell}$  dropped. These applied voltages were high enough for severe electrochemical reactions which resulted in bubble generation and electrode degradation. On NSP-EP chips, due to low voltage operation; high  $\eta_{EP}$  and  $\phi_{cell}$  (>90%) were achieved without bubble generation.

#### 3.10. Phase diagram

Electroporation is a threshold phenomenon; EP occurs successfully when  $V_a$ ,  $t_p$  and  $P_n$  are well above a critical value. But if these values are too high, the cell will undergo an irreversible process and will be unable to reseal and repair changes and lysed. It is very important to define the boundary for non-EP, EP, electric cell lysis regions. The critical electric field strength for EP ( $E_{EP}$ ) for the pulse duration is defined as the electric field strength at the onset of increasing slope of the EP efficiency curve for that pulse duration. The  $E_{EP}$  for suspended HeLa cells for single electric pulse is 1.6 kV/cm (2.3 V) for 2 ms, 1.3 kV/cm (1.9 V) for 4 ms, 1.16 kV/cm (1.5 V) for 6 ms, and 1.03 kV/cm (1.3 V) for 8 ms (see SI, Fig. S4). These critical values were even lower at higher pulse number for specific pulse duration (see SI, Fig. S5). Critical electric field strength for electric cell lysis ( $E_{CL}$ ) is also defined to set the boundary between EP and cell lysis regions.

Experiments were carried out on NSP-EP chips ( $\alpha$  = 7.55) and  $V_{EP}$ ,  $E_{EP}$ ,  $V_{CL}$  and  $E_{CL}$  were determined for different pulse widths ( $t_P$ ) and pulse number ( $P_n$ ). These values were used to construct "phase diagram" for EP of HeLa cells on NSP-EP chips (Fig. 6). Phase diagram defines the boundary for the non-EP region, EP region and electric cell lysis region based on  $E_{EP}$  and  $E_{CL}$  at different  $t_P$ 

and  $P_n$ . Phase diagram can be used for the optimization of electrical parameters for efficient EP with reasonable cell viabilities. Clearly,  $E_{EP}$  was achieved at lower voltages by increasing  $t_P$  and even ultra-low voltages by increasing  $P_n$ . Minimum  $V_{EP}$  ( $V_{EP,min}$ ) is obtained at 0.8 V with  $P_n$  of 10 and  $t_P$  of 6 ms or above. The low-voltage NSP-EP chips are highly attractive for the integration of the other  $\mu$ -TAS functions, such as electric cell lysing, electrical detection of biomolecules and cancer cells [60,62,65]. Based on these low voltage NSP-EP devices, we recently developed "Smartphone-based Electroporator system" in which optimized EP protocols for different types of cells and molecules in a control app of an Android smartphone can be applied to micro/nano EP chips through an open-source MCU (Arduino) with an integrated Bluetooth module [49].

#### 4. Conclusions

In this paper, we present a highly ordered 3D scalable nanospike electroporation platform for efficient intracellular delivery with high cell viabilities at low pulse amplitude and duration, which minimized undesirable electrochemical reactions and electrolysis significantly and increase the device's reliability and cell viabilities. Highly ordered 3D nano-spikes arrays were fabricated with controllable geometries using simple, scalable, reproducible and cost-effective electrochemical anodization and etching processes. Due to scalability of the fabrication process. 3D NSPs were fabricated on chips for handling small populations as well as on wafer level for large scale processing. Electroporation at reduced voltages was observed due to electric field enhancement at highaspect-ratio nano-spikes as compared to the PEP devices without nano-spikes. High EP efficiencies and cell viabilities (> $93 \pm 6\%$ ) were achieved at low voltages (2 V) on NSP-EP chips by optimizing electric pulse protocol and nano-spikes dimensions. This applied voltage is more than ten times lower as compared to PEP devices. Due to low voltage operation on NSP-EP chips; EP was carried out without bubble generation. Due to high voltage operation on planar electroporation (PEP) devices, bubble generation was observed. The EP phase diagram was constructed by determining critical electric fields for non-EP, EP and cell lysis for different electric pulse parameters. Minimum voltage required to generate a critical electric field to induce EP was obtained at 0.8 V for a pulse number of 10 and pulse duration of 6 ms or above. This is more than sixteen times lower as compared to PEP devices. Simple, low-cost and scalable fabrication process for high-aspect-ratio nano-spikes along with low voltage operation can enable the integration of digital miniaturized electroporator to µ-TAS, LOC and smartphone systems.

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#### Appendix A. Supplementary data

Supplementary data associated with this article can be found, in the online version, at http://dx.doi.org/10.1016/j.sna.2016.12.022.

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